



COPY OF PAPERS
ORIGINALLY FILED

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: PELLEGRIN, Yvon; HERNANDEZ, Jose; CLAUDE, Richard; HALE, William

SERIAL NO.: 09/831,225

FILED: June 28, 2001

TITLE: ELECTROSTATIC MAINTAINING DEVICE

PRELIMINARY AMENDMENT

Commissioner of Patents
and Trademarks
Washington, D.C. 20231

Sir:

In conjunction with the filing of the present application, and prior to an initial Official Action on this matter, please amend the above-identified application as follows:

IN THE SPECIFICATION

On page 1, please substitute the paragraph beginning with "Electrostatic" and ending with "holding device", as follows:

b1 Electrostatic Maintaining Device

On page 1, please substitute the paragraph beginning with "The invention" and ending with "vacuum, for example.", as follows:

BACKGROUND OF THE INVENTION

1. Field of the Invention

b2 The present invention presented here involves an electrostatic maintaining device specifically designed to hold wafers of conductor or semiconductor materials such as silicon while they undergo micro-manufacturing or any other type of treatment such as plasma treatment in an enclosure under vacuum, for example.

On page 1, please substitute the paragraph beginning with "The different treatment" and ending with "automated mechanisms.", as follows:

RECEIVED
MAY 16 2002
1C 2800 MAIL ROOM

#913
2836
Pre-Amendment B
ROBINSOY
6/1/02